

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yasuji HIRAMATSU, et al.

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HEREWITH

INTERNATIONAL APPLICATION NO.: PCT/JP01/05791

**INTERNATIONAL FILING DATE: July 4, 2001** 

FOR: HOT PLATE FOR SEMICONDUCTOR PRODUCING/EXAMINING DEVICE

## REQUEST FOR PRIORITY UNDER 35 U.S.C. 119 AND THE INTERNATIONAL CONVENTION

Assistant Commissioner for Patents Washington, D.C. 20231

J. Lewon #5 11/19/2002

Sir:

In the matter of the above-identified application for patent, notice is hereby given that the applicant claims as priority:

COUNTRY Japan <u>APPLICATION NO</u> 2000-202510

DAY/MONTH/YEAR

04 July 2000

Certified copies of the corresponding Convention application(s) were submitted to the International Bureau in PCT Application No. PCT/JP01/05791. Receipt of the certified copy(s) by the International Bureau in a timely manner under PCT Rule 17.1(a) has been acknowledged as evidenced by the attached PCT/IB/304.

Respectfully submitted, OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

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